

Integrating

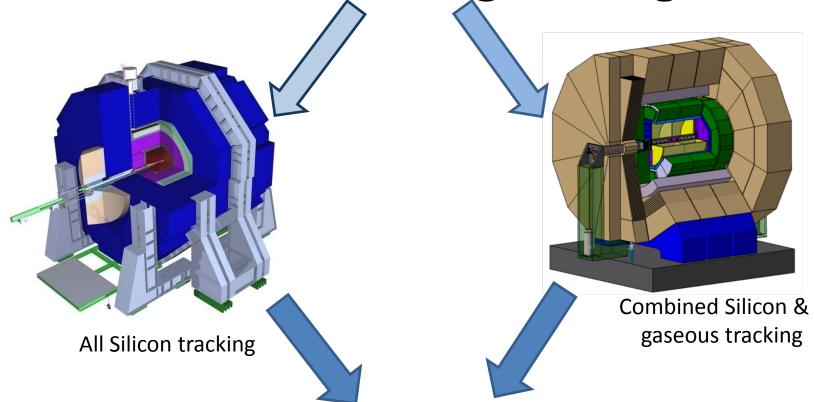
Silicon tracking in ILC detector concepts: solutions & challenges

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The work reported here is done within the SiLC R&D collaboration and EUDET project and the ILD concept plus collaborative contacts with SiD.



Two tracking strategies



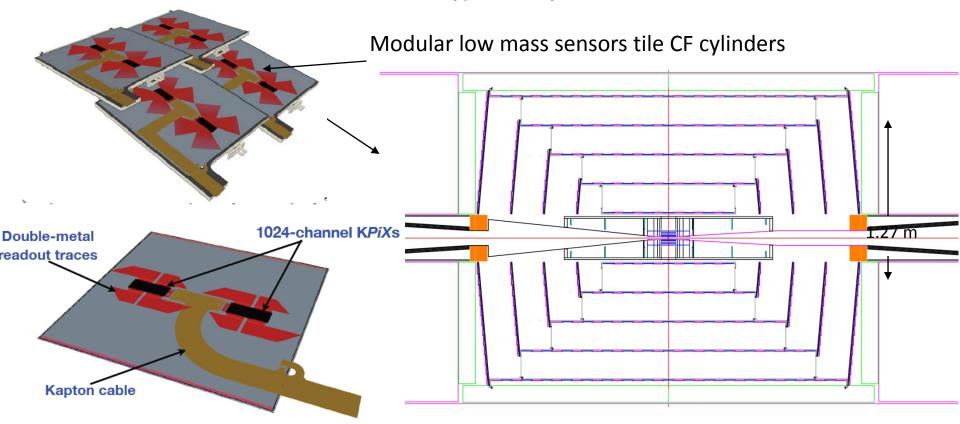
Two integration solutions: Differences but still many common issues

The LOIs submission triggered a lot of activities & progress in this field that must be pursued!

An All Silicon tracking case



~100 m² Si Strips: Barrel single sided (r-φ); endcaps double sided



~10 cm x 10 cm; 320 μ m thick; 25 μ m sense pitch; 50 μ m readout (prototype fabricated); S/N > 20; <5 μ m hit resolution

Bump bonded readout with 2 KPiX chip; no hybrid

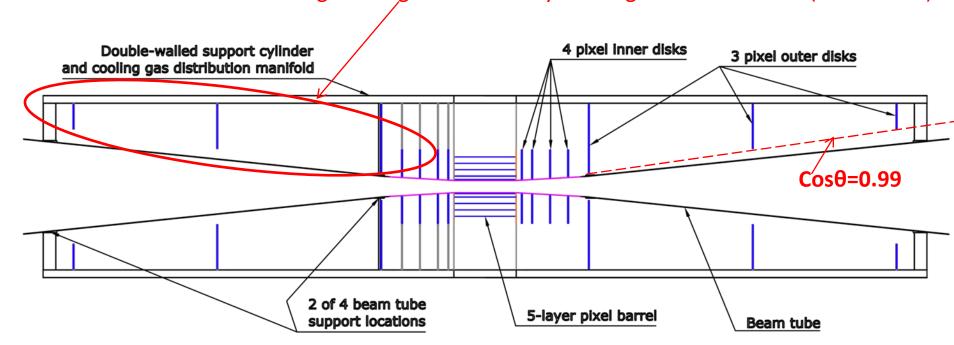
KPiX measures amplitude and bunch # in ILC train, up to 4 measurements per train Pulsed Power: 20 μW/channel avg; ~600 W for 30 M channels; gas cooling

(From SiD LOI talk)

The inner tracking part of SiD

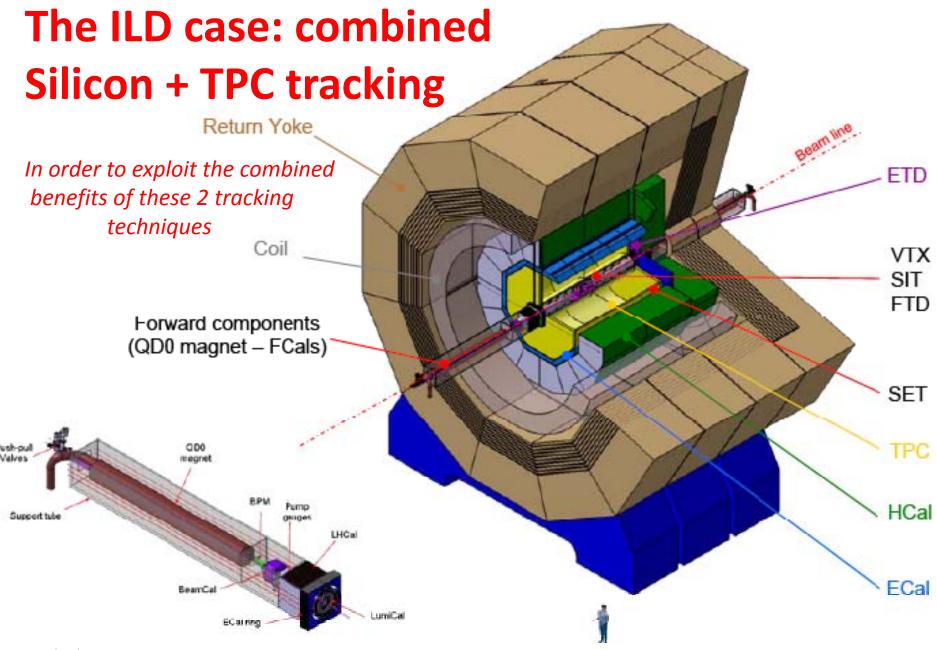


In their latest designs, all ILC detector concepts are introducing a few more forward disks in order to ensure the ensure the tracking coverage down to very low angle w.r.t beam axis (see also 4th)



- Around the beam pipe two 4-plane end disk assemblies and three additional disks per end for extended coverage.
- All elements are supported indirectly from the beam tube via double-walled, carbone fiber laminate half cylinder.
- Sensor thickness of 75 μ m assumed, with 20 x 20 μ m² pixel size

(Courtesy M. Demarteau)



Integration of a Silicon system into the ILD concept: remarks

The construction and the integration of a Silicon tracking system, part of an hybrid tracking ensemble (CDF, ATLAS) is much more challenging than an all-Silicon fully integrated system (CMS, SiD and futur s-ATLAS). Among the main challenging issues:

> THE SPACE ALLOCATED:

An all-Silicon system has all the tracking space for it alone (1.2m radius or so) Hybrid: only 2cm for the SET, 4cm for the ETD, 20-25cm for SIT+FTD

>THE FIXATION and SUPPORT STRUCTURE:

All Si can build the support structure as desired as well as its own fixing system.

Hybrid: the Si device fully depends on the restricted space and the surroundings.

>THE ROLE:

All Silicon system must primarily fulfill the role of a highly performing tracker i.e. in momentum and spatial resolution measurements.

Hybrid case: the Si component must provide additional functions: alignment, time stamping, handling of distortions of the gaseous detector etc....

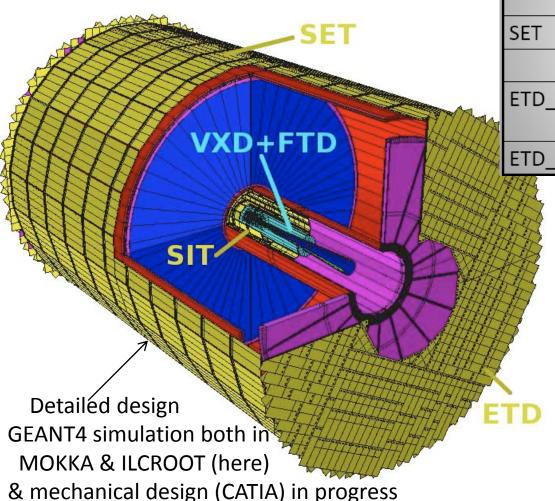
- > ALIGNMENT: "global" in the all Si case, "mixed-mode" in the hybrid case.
- **COOLING**: here also much more constraining in the hybrid case (much more dependant on the neighbors)



The Silicon Envelope in numbers

(current scheme)





Component	Layer #	# modules	# sensors/ module	# channels	Total surface m2
SIT1	1 st layer	33	3	66.000	0.9
	2 nd layer	99	1	198.000	0.9
SIT2	1 st layer	90	3	180.000	2.7
	2 nd layer	270	1	540.000	2.7
SET	1 st layer	1260	5	2.520.000	55.2
	2 nd layer	1260	5	2.520.000	55.2
ETD_F	X or U or V	82/quad =328/layer =984/ETD	2 or 3 or possibly 4	2.000.000	30
ETD_B	idem	idem	idem	idem	30

Total number of channels:

 $10^6 (SIT) + 5x10^6 (SET) + 4x10^6 (2 ETD)$

= **10 x10**⁶ channels

Total area:

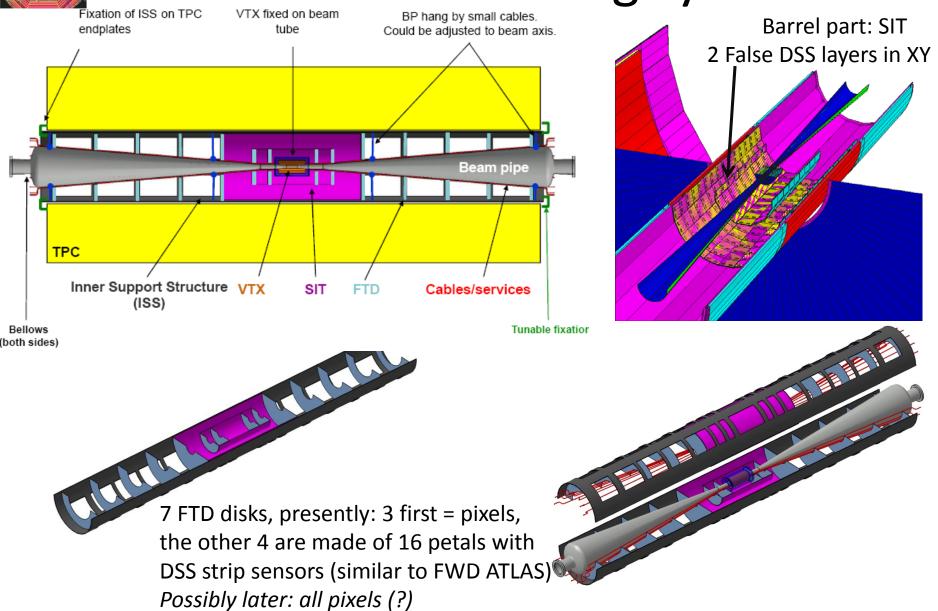
7 (SIT)+110 (SET) +2 \times 30(ETDs) = 180 m²

Total number of modules:

500 (SIT) + 2500 (SET) + 2000 (ETDs)=

5000 modules with unique size sensors

ILD inner Si tracking system



Beam pipe

SIT

FTD

VTX

SUPPORT STRUCTURE OF SIT+FTD

The VTX is fixed to the beam pipe and includes its own envelope

The SIT and FTD are fixed to the support structure which itself will be fixed to the TPC: middle plan and on the two edges

There is for ALL the Silicon components only one cable path, i.e. the one along the beam pipe as sketched here below

Cables

Support structure

Courtesy of M. Jore

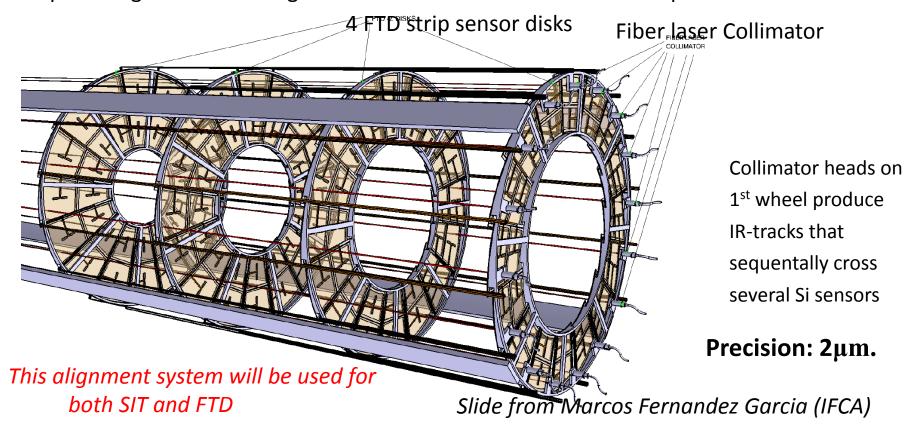


ALIGNMENT (IMB-CNM & ICFA)

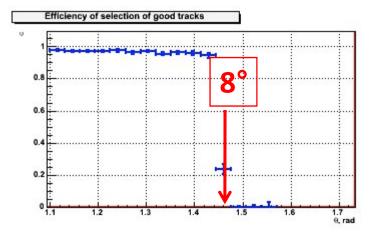


Concept of IR alignment system: use IM beams as infinite momentum tracks. (AMS, CMS Selected sensors are traversed by IR beams.

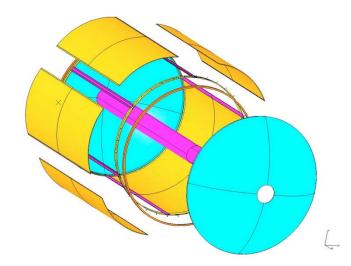
These beams are then measured as particle tracks and a first order alignment scenario is obtained. The rest of sensors are aligned using particle tracks. The transference of coordinates from optical aligned to track aligned modules is done via sensor overlap.



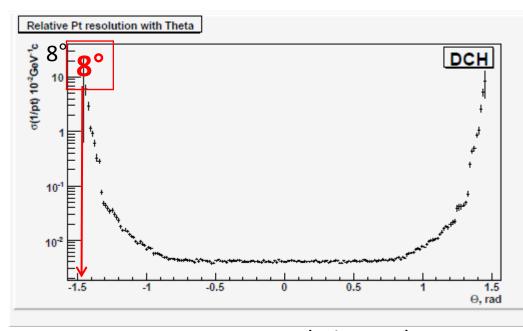




Drift chamber efficiency vs theta



Nobody is perfect



Momentum resolution vs theta

Courtesy F. Grancagnolo (CLUCOU in 4th)



4/19/2009



THE SILICON EXTERNAL TRACKER: SET



Diego Gamba and Paolo Mereu (Torino)

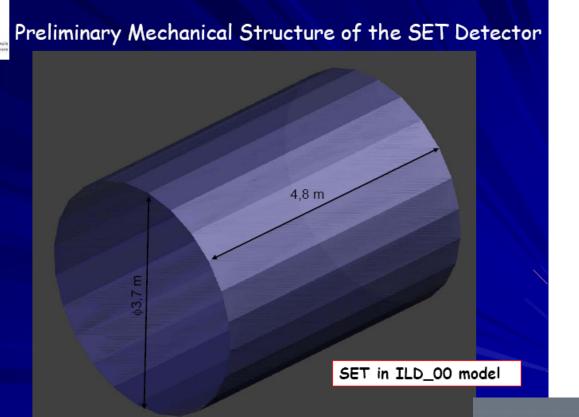
The mechanical structure of the SET is studied in details by the Torino team a real progress was made these last few months.

After a certain number of preliminary designs and studies, P. Mereu and D. Gamba have come to the following basic design:

The mechanical structure of the SET is made by 2 halves composed of 24 panels 2,4x0,48m. Each panel is independently fixed at both short sides to the outer surface of the TPC structure, thus avoiding an additional outer frame and therefore keeping the material budget at its minimum.

Static deflection with a payload of 1kg/sqm is given in the following slide.

Silicon detectors are fixed on the surface of each panel; details of this fixation are being studied.



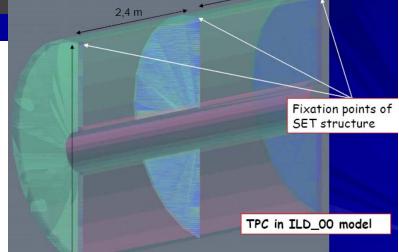


2 halves composed of 24 panels 2,4x0,48m. Torino will built such a panel as demonstrator and to study all related issues

Each panel is independently fixed at both short sides to the outer surface of the TPC structure

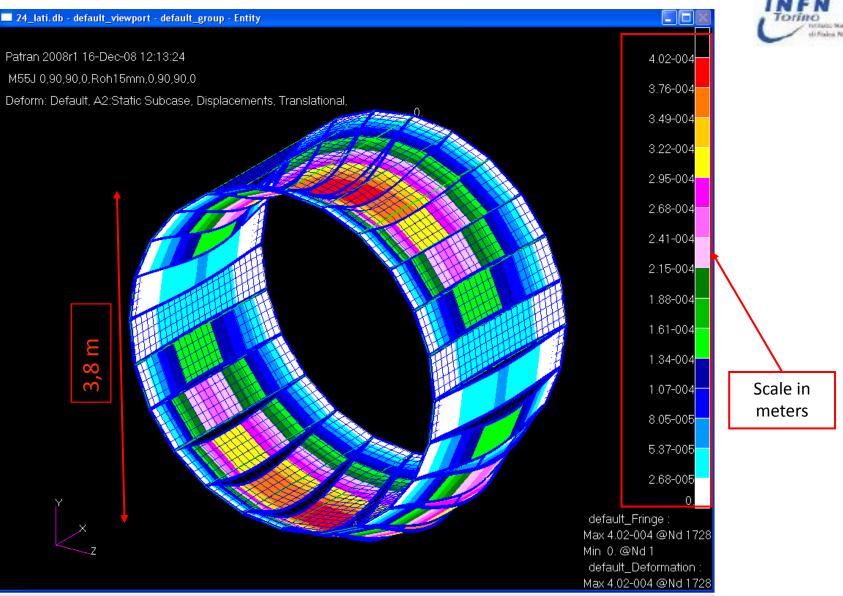
8th SILC Meeting - IFCA Santander

17-19 December 2008

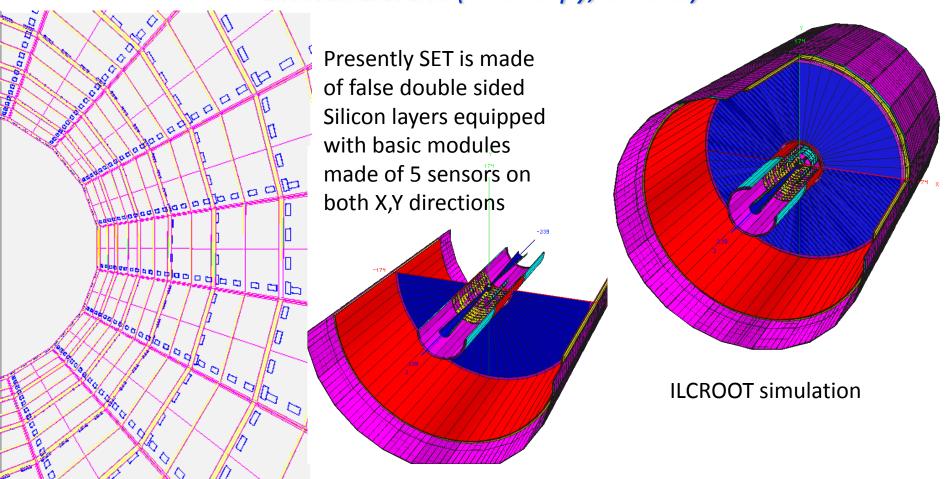


paolo.mereu@to.infn.it

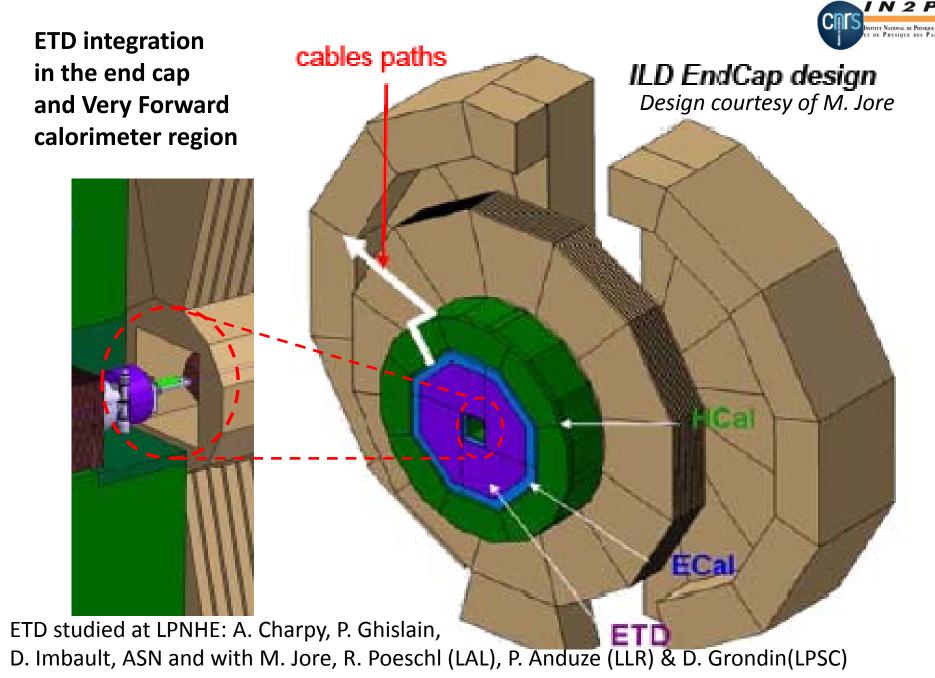




SET: Study of design implementation with detailed simulation (A. Charpy, LPNHE)

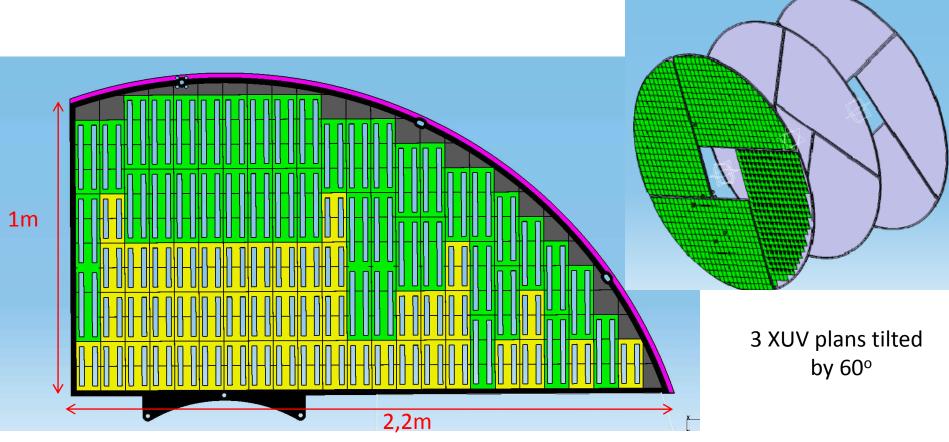


Challenging issues: alignment (the positioning on the TPC wall must be precise at $100\mu m$) well monitored wrt SIT could/should be refined with a few tens of μm (under study). Power dissipation from calorimeters? Vibrations? Etc... Issues to be studied.



One quadrant of XUV end cap: present design



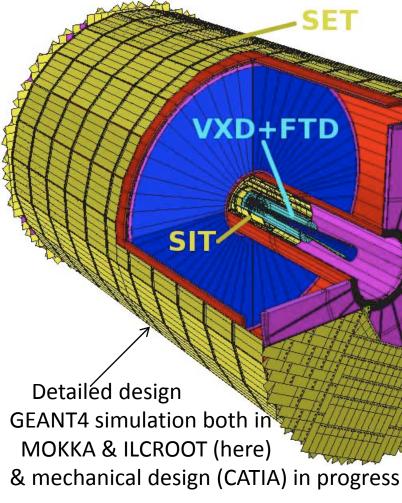


Made of modules with 2 (yellow) or 3 (green) sensors. (current design, rapidly evolving) 12 quadrants per XUV triplets. Thus 24 in total. Fixed via a C fiber membrane to the e.m. calorimeter; Positioning screw with precision of the order of 100 μ m, light but very precise. A mechanical prototyped quadrant will be built and tested with mechanical proto of e.m.



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Total number of channels:

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Total area:

7 (SIT)+110 (SET) +2 \times 30(ETDs) = 180 m²

Total number of modules:

500 (SIT) + 2500 (SET) + 2000 (ETDs)=

5000 modules with unique size sensors =>Achieved: a unified and simple design

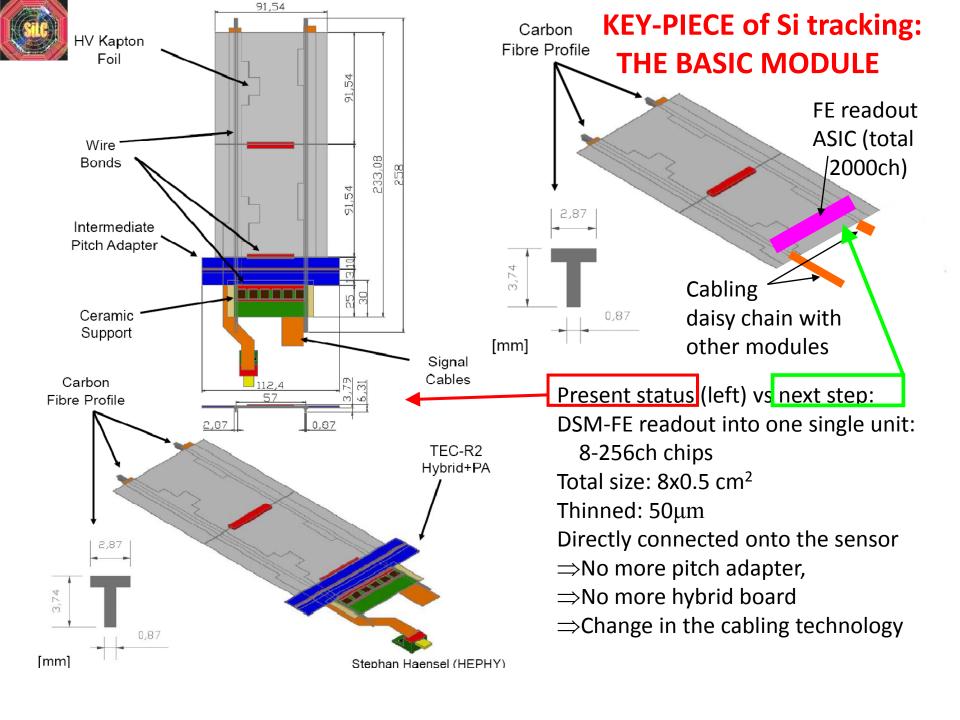
for all components (except FTD)

Common issues and challenges

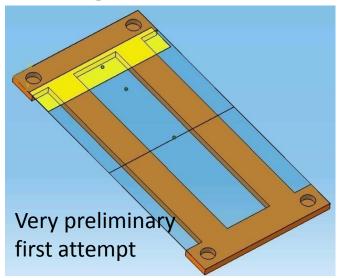
- The basic module (see next slides)
- The sensors (see next slides)
- The forward Si tracking (converging scheme)
- The FEE and direct connection to the sensor (see next talk)
- Power cycling (next talk)
- Effect of high B-field (vibrations) : NOT YET (will be tested with new chips)
- The support structures √
- The modularity: **√**
 - => towards a unique sensor type in the present ILD design for all components but FTD and repetitive elements of construction (super-modules) : ▼
 - => or a unique module size (SiD) at least in the central barrel (the End Caps:??): V
- The cooling (studies ongoing since a few years on Si prototypes –SILC- need combined tests with other sub-detectors mechanical prototypes (foreseen)
- The alignment techniques
- The stability, robustness, reliability (under study)
- Calibrations, monitoring, push pull issues (under study or development)

Even if alternatives are looked for by the different detector concepts, the issues and often the solutions to them are rather similar. A lot of work underway within SiLC.

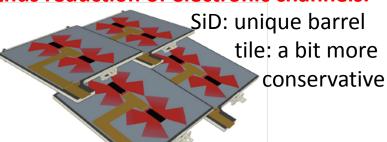
A few examples have been already shown and a few more here after.

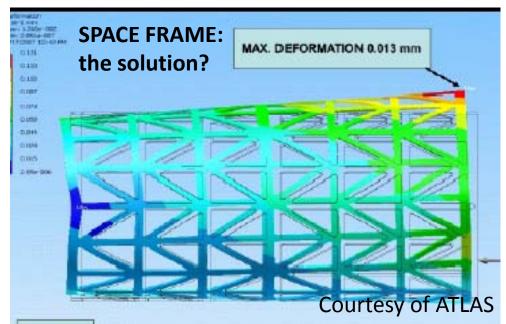


Light modules and supports: the diet...



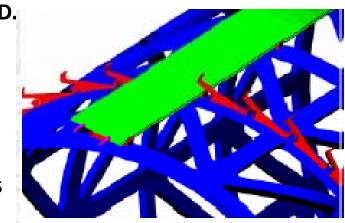
SiLC (ILD) develops very light modules, with edgeless sensors (no overlay => challenging alignment btw modules) & variable strip length (exploit ILC cycle) thus reduction of electronic channels.





Detailed architecture of the support structure in

progress at ILD.
Super-module
to be built by
Torino (SET) &
Paris(ETD) for
studying the
pending issues





R&D on sensors roadmap

➤ Strip sensors: in progress

"Standard strips" but: larger wafers 6" → 8",

thinner: $300 \rightarrow 200 \mu m$, pitch: $50 \mu m$

Edgeless:

Planar 6", 50 μm pitch, ≤ 200 μm thick and 3D Planar

► Strip sensors for alignment: in progress

Standard specially treated Novel technology

>Smaller sensors granularity (also wrt CLIC)

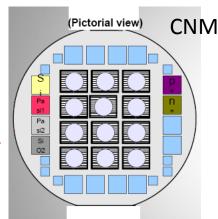
follow SLHC developments ex: strixels

Pixels: 3D technology based (Low Material Budget

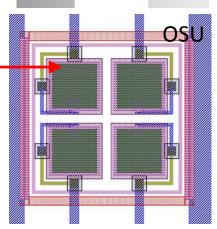
& High Gain Pixels by OSU) & joining the worldwide effort

- *▶Inherited expertise* on detailed testing: *test structures*
- > Newly developed refined tests at the test beams





IRST

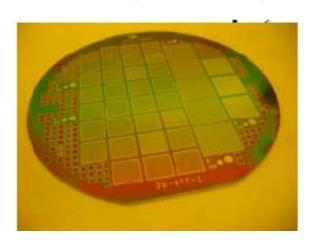


Università degli Studi

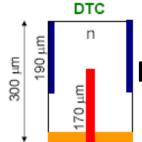


3D-DTC-1 batch

- N-type substrate
- (Mostly) microstrip detectors useful to ease characterization and investigate process yield



Column overlap not optimized: about 60um



NEW SENSORS R&D:

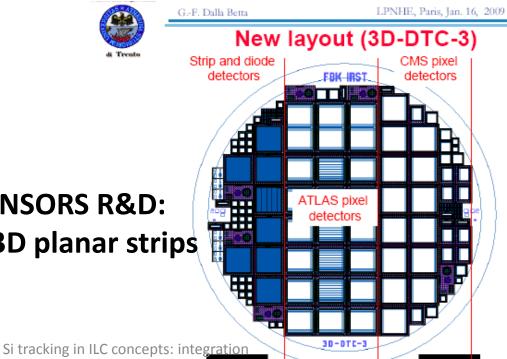
R&D on 3D planar strips

Fabrication

- 2 batches under fabrication at FBK
- 1) Recycle of 3D-DTC-2: n-on-p, 200-μm thick substrate, nonpassing-through columns (180 μm)
 - Currently at 2nd DRIE etching, to be completed by 02/09.
- 2) 3D-DTC-3: n-on-p, 250-µm thick substrate, full 3D detectors (passing-through) columns.

New double-sided process defined, no need for support wafer, also suitable for dual read-out pixel/strip.

Just started, to be completed by 04/09



Courtesy G. F. Dalla Betta



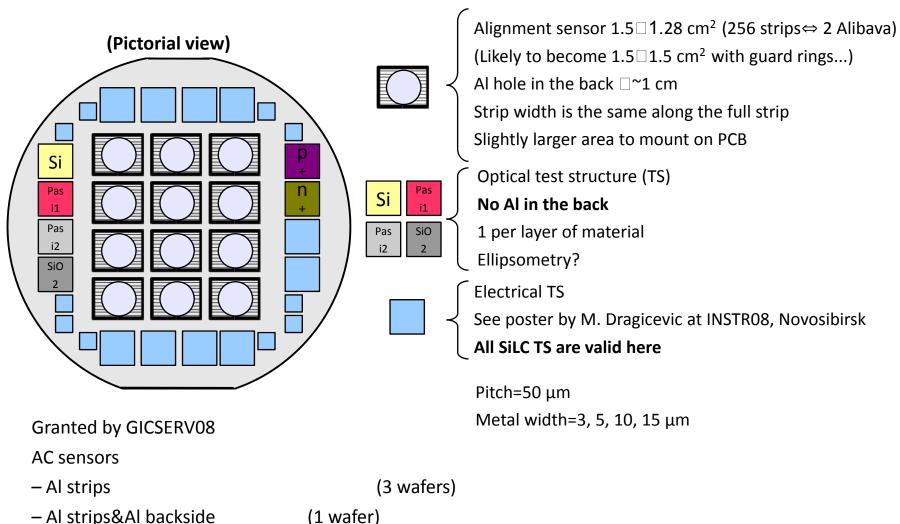


NEW SENSORS R&D (cont'd)



IMB-CNM (Barcelona) is producing the first sensor prototypes with multi-geometry and optimum

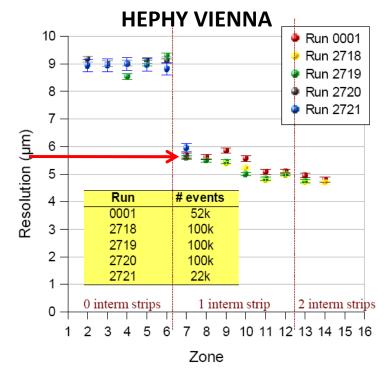
thickness. Tentatively scheduled for test beam in August 2009 (?)



Test bench to measure sensor detailed performances



New series of tests in 2009 at CERN with novel sensors from IMB-CNM and from Poland with wire bonded chips. Expertise & experienced teams: asset



Th. Bergauer, S. Haensel, M. Krammer et al.(HEPHY)

(CU Prague)

Concluding remarks

- The LOI gave a serious boost in developing realistic scenarios for integrating the Si tracking in the various detector concepts.
- Two Si tracking scenarios: with or without gaseous detector;
 The all-Si case is much simpler for integrating than the hybrid or combined case.
- But there are many common issues with often similar solutions in both schemes.
- This reinforces the interest of having an horizontal R&D that addresses these issues on common basis and gather the efforts of many teams to work on the best possible solutions.
- Moreover the test beams and prototypes developments are instrumental as well as the combined tests with other subdetectors. There also an horizontal R&D helps in merging the efforts.
- The dynamics created with the LOIs should not be lost!!